

Application for United States Letters Patent
for
Conditional Burn-In Keeper for Dynamic Circuits
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Field

[0001] Embodiments of the present invention relate to digital circuits, and more particularly, to dynamic circuits.

Background

[0002] The functionality and reliability of microprocessors are usually tested under conditions that are relatively extreme when compared to normal operating conditions. During testing, the temperature and supply voltage may exceed the upper bounds of their respective target operating ranges. This is often referred to as burn-in or stress testing.

[0003] The burn-in process may set a severe constraint on dynamic circuits, requiring relatively large keepers during burn-in to compensate for additional leakage currents due to the higher temperature and supply voltage. Leakage currents are relatively small currents present when a transistor is not fully turned ON, e.g., when the magnitude of the gate-to-source voltage is less than the transistor's threshold voltage. Leakage current may present more of a design problem as transistor sizes are made smaller. Although larger keepers may meet the burn-in condition while compensating for leakage currents in the dynamic circuit, they nevertheless would be oversized for normal operating conditions. Using larger keepers during normal operating conditions may degrade microprocessor performance.

[0004] The prior art circuit of Fig. 1 provides a conditional keeper for burn-in, and a normally sized keeper during normal operation, so that the burn-in conditions are met without degrading the performance of the microprocessor during normal operation. See D. Stasiak, et al., "A 2nd Generation 440ps SOI 64b Adder," ISSCC 2000, pp. 288-289.

[0005] For simplicity, only one stage of a dynamic circuit is shown in Fig. 1. Network 102 represents a plurality of nMOSFETs (Metal Oxide Semiconductor Field Effect Transistor) configured to conditionally pull node 110 LOW during an evaluation phase so as to synthesize the particular logic function that is desired. During an evaluation phase, pMOSFET 104 is OFF, and during a pre-charge phase, pMOSFET 104 is ON to pull node 110 HIGH. Network 102 in general will have a plurality of input ports for receiving digital voltages, perhaps from other stages in the dynamic circuit.

[0006] Inverter 106 and pMOSFET 108 are configured as a keeper (or half-keeper), so that during an evaluation phase node 110 is kept HIGH if network 102 does not pull node 110 LOW. Static CMOS (Complementary Metal Oxide Semiconductor) 116 may be a static inverter or other logic gate, whose output may be provided to another stage of the dynamic circuit.

[0007] Inverter 106 and pMOSFET 108 are sized for normal operating conditions. The two stacked pMOSFETs 112 and 114, together with inverter 106, comprise what may be referred to as a conditional keeper for burn-in testing. pMOSFETs 112 and 114 are sized appropriately for the operating conditions of a burn-in test. The gate of pMOSFET 114 is activated by a signal BI-active (Burn-In active), where BI-active is set HIGH when the microprocessor is operating normally, and is set LOW during a burn-in test. With BI-active set LOW, pMOSFET 114 is ON, and inverter 106, together with pMOSFETs 112 and 114, act as a keeper, properly sized for the burn-in conditions.

[0008] Stacking MOSFETs, i.e., connecting the drain of one to the source of the other, reduces their overall effective gain. Because pMOSFETs 112 and 114 are in a stacked configuration, they should be sized up approximately twice as large as compared for a single, non-stacked pMOSFET keeper in order to compensate for the reduced gain. However, sizing up pMOSFETs 112 and 114 may have some disadvantages. Sizing up pMOSFETs 112 and 114 uses a larger chip (die) area. Also, the larger size increases the load on inverter 106, which may degrade the response of pMOSFET 108 when performing its standard keeper operation during normal operation conditions. As a result, inverter 106 may also need to be sized larger, which in turn increases the load on node 110, which may result in an increase in switching power and delay of the dynamic gate.

Brief Description of the Drawings

[0009] Fig. 1 is a prior art circuit for a stage of a dynamic circuit with a conditional keeper for burn-in.

[0010] Fig. 2 is a stage of a dynamic circuit with a conditional keeper for burn-in according to an embodiment of the present invention.

Description of Embodiments

[0011] Fig. 2 is a circuit according to an embodiment of the present invention, where again for simplicity only one stage of a dynamic circuit is shown. Network 202, pMOSFET 204, and static CMOS 216 provide the same function as network 102, pMOSFET 104, and static CMOS 116, respectively, in Fig. 1. Inverter 206 and pMOSFET 208 comprise a keeper to keep node 210 HIGH if it is not pulled LOW by network 202 during an evaluation phase. NAND gate 218 and pMOSFET 220 comprise a conditional keeper for burn-in. Input port 222 of NAND gate 218 is connected to node 210, and input port 224 of NAND gate 218 is provided with a signal BI-active#, where BI-active# is the complement of BI-active, so that BI-active# is HIGH (BI-active is LOW) during a burn-in test, and BI-active# is LOW (BI-active is HIGH) during normal operation.

[0012] It is seen that during burn-in, pMOSFET 220 will also keep node 210 HIGH if it is not pulled LOW by network 202 during an evaluation phase. It is preferable that pMOSFET 220 should be sized so that the combination of pMOSFET 220 and pMOSFET 208 provides a sufficiently strong keeper to compensate for additional leakage currents due to burn-in testing.

[0013] For some embodiments, the size of pMOSFET 220 may be made four times smaller than the total size of pMOSFETs 112 and 114, while still compensating for increased leakage currents during burn-in testing. The activation signal BI-active# may be viewed as a DC signal, so that it does not set a constraint on the size of NAND gate 218. The size of NAND gate 218 is set by the target transient response for pMOSFET 220, however for some embodiments pMOSFET 220 may be up to two times smaller than pMOSFET 114. Thus, for some embodiments the total size of NAND gate 218 together with pMOSFET 220 is close to the size of inverter 106 in the prior art, and therefore the total area of the conditional keeper in Fig. 2 may be significantly less than that of the prior art.

[0014] Often, the burn-in process tests for reliability and functionality, rather than performance. Consequently, the dynamic circuit may be operated at a lower frequency during a burn-in test than when operated under normal operation conditions. In such cases, performance requirements may be relaxed during the burn-in test, so that the speed

